

Papers and events of interest that include Fractilia authors.

SPIE Advanced Lithography Conference, February 27 – March 2, 2023, San Jose, CA.

	Paper	Location	Title	Presenter
Sunday				
8:30 am	Short Course SC1263		Stochastic Lithography short course	Chris Mack, John Petersen
Monday				
2:30 pm	12496-7	Grand Ballroom 220B	Overlay and edge placement error metrology in the era of stochastics	Chris Mack, Fractilia
Tuesday				
4:50pm	12496-28	Grand Ballroom 220B	Measurement and analysis of variations in via measurements using critical dimension scanning electron microscopes and e-beam massive metrology techniques	Genevieve Kane, IBM
Wednesday				
10:40 am	12498-32	Grand Ballroom 220C	MOx resist formulation, chemistry, and processing impacts on the power spectral density of line-edge roughness	Amrit Narasimhan, Inpria